

# MULTEM image simulation software

## Worksheet

Dr. Ivan Lobato, Annelies De wael and Thomas Friedrich

{ivan.lobato, annelies.dewael, thomas.friedrich}@uantwerpen.be

## 1 Introduction

MULTEM is a software for performing transmission electron microscopy image simulations, developed at EMAT [Lobato and Van Dyck, 2015, Lobato et al., 2016]. This worksheet explains the features of MULTEM through a series of practical examples. This tutorial will run through the graphical user interface of MULTEM step by step. As we go along, you will run some examples, to experience hands-on what the effect of the different parameters is.

### 1.1 Installation

The MULTEM software can be found at the following link: <https://github.com/Ivanlh20/MULTEM>. The folder MULTEM contains all specimen files you will need in this tutorial, and the software. Open the folder and double click on the executable multem.exe

In this folder, you will also find Matlab scripts to run the MULTEM software. The same settings that can be changed in the graphical user interface, can also be changed in these scripts.

### 1.2 Theory

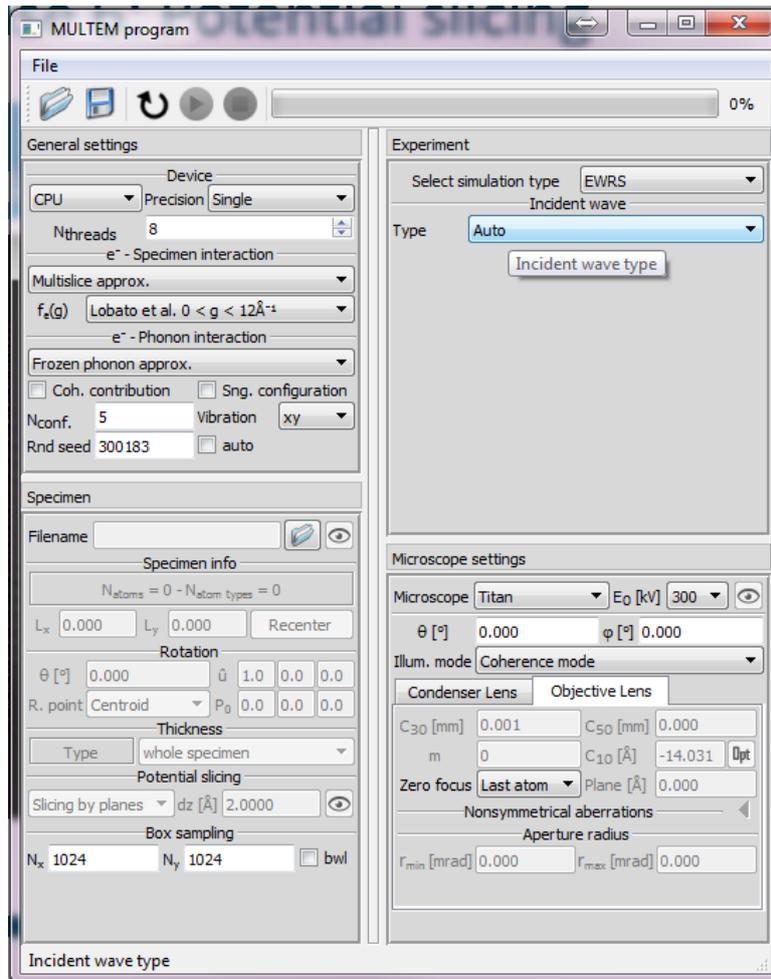
An introduction to the theory of electron microscopy can be found in [De Graef, 2003]. Furthermore, we recommend [Kirkland, 2010], a book specifically about transmission electron microscopy simulations.

## 2 Graphical user interface

The graphical user interface of MULTEM consists of 4 separate panels: *General settings*, *Specimen*, *Experiment* and *Microscope settings*. Initially, some default settings are prefilled. When you walk through these panels, one by one, the information required to set up your image simulation can be changed in an intuitive order. When you hover over a parameter in any of these windows, an information box appears. The same explanation for the parameter is also shown at the lower left bottom of the interface. This can also be seen in Figure 1. After running through all separate panels, you can start the simulation with the green start button. The image simulation can be stopped with the red stop button. The result of your simulation will appear in a new window. All the results can be saved as tif images or as binary format file by right clicking on the image. Furthermore, you can always return to the default values of MULTEM by clicking on the circular arrow.

In this tutorial, we will walk you through some possibilities that MULTEM has to offer for (S)TEM image simulations. You may notice that some options are disabled. These options will become available in future releases of the MULTEM program.

**Throughout this tutorial, all exercises will start from the default values.**



**Figure 1:** MULTEM graphical user interface, divided into 4 panels: *General settings*, *Specimen*, *Experiment* and *Microscope settings*. When you hover with your mouse over a parameter, the explanation is shown in a box and at the bottom left, as is shown here for the *incident wave type* in the *Experiment* panel.

## 2.1 Microscope settings

In this lower right hand side panel of the MULTEM graphical user interface, you can set up the microscope parameters, which determine the incident wave function and the shape of the probe. We will therefore start this tutorial with exercises without a specimen. This can be done by choosing simulation type IWRS (incident wave in real space).

You can choose the acceleration voltage. Note that in the forward scattering approximation, image simulations for low acceleration voltages are less accurate.

### Set-up for exercise 1: Acceleration voltage

🔄 Set default values

- Experiment
  - Select IWRS
- Microscope settings
  - Set  $E_0 = 80$  kV

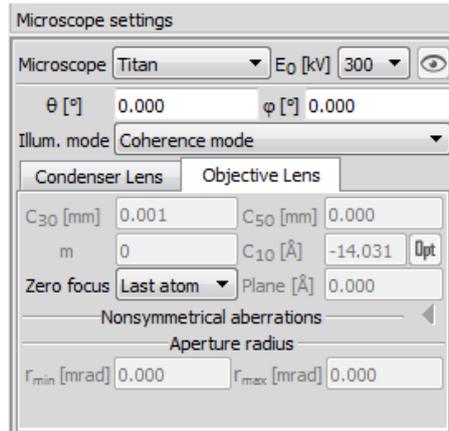
### Exercise 1: Acceleration voltage

▶ Run the simulation for  $E_0 = 80$  kV.

Leave the image open. Change the acceleration voltage to 300 kV.

▶ Run the simulation and compare.

Furthermore, you can indicate the orientation of the incident beam using spherical coordinates  $\theta$  and  $\varphi$ . You can also choose your illumination mode: *coherence mode*, *partial coherence mode*, or *incoherent numerical integration*. The default setting of the illumination mode changes depending on the selected simulation type.



**Figure 2:** The lower right panel of the MULTEM graphical user interface allows to describe the settings of the microscope, such as acceleration voltage, orientation of the incident beam, illumination mode, and different types of aberrations for the objective and/or condenser lens.

Next, you enter information about the condenser lens and/or the objective lens. Depending on the selected simulation type (STEM, HRTEM, ...), some parameters will be blanked.

In HRTEM, the relevant lens for imaging is the objective lens. You can indicate the third order spherical aberration  $C_{30}$ , fifth order spherical aberration  $C_{50}$ , vortex momentum  $m$ , and the defocus  $C_{10}$ . For the defocus, a button *Opt* exists to put the defocus equal to the optimal Scherzer defocus.

You can choose the reference for the defocus. Possible options are putting the zero defocus at the *first atom*, at *half thickness*, at the *last atom* or at a *user defined* plane, to be entered in the box next to the drop-down menu for zero focus. Furthermore, you can enter a value for the defocus spread, if you have chosen for the partially coherence mode or the incoherent numerical integration.

In STEM, the relevant lens for imaging is the condenser lens. For this lens as well, you can now enter the symmetric aberrations mentioned before. Concerning the reference point for the defocus value, we now have less options, since this lens sits above (before) the specimen. We can therefore choose to focus at the *first atom* or at a *user defined* plane.

## Exercise 2: Aberrations

### Set-up for exercise a: Defocus

- ↻ Set default values
  - Experiment
    - Select IWRS
  - Microscope settings
    - $C_{10} = -100 \text{ \AA}$

### Exercise a: Defocus

- ▶ Run the image simulation.  
Leave the image open. Change the defocus to  $C_{10} = 100 \text{ \AA}$
- ▶ Run the simulation and compare the images  
Leave the image open. Optimise the defocus by pushing the *Opt* button (Scherzer defocus)
- ▶ Run the simulation and compare the images.

### Set-up for exercise b: Spherical aberration

- ↻ Set default values
  - Experiment
    - Select IWRS
  - Microscope settings
    - $C_{30} = 0.010 \text{ mm}$
    - Optimise the defocus by pushing the *Opt* button (Scherzer defocus)

### Exercise b: Spherical aberration

- ▶ Run the image simulation.  
Leave the image open. Change the spherical aberration to  $C_{30} = 0.1 \text{ mm}$ .
- ▶ Run the simulation and compare the images to see the effect of the amount of spherical aberration.  
Now optimise the defocus and compare the wave again.
- ▶ Run the simulation.

### Set-up for exercise c: Two-fold astigmatism

↻ Set default values

- Experiment
  - Select IWRS
- Microscope settings
  - Unfold the nonsymmetrical aberrations of the condenser lens and set  $C_{12} = 20 \text{ \AA}$

### Exercise c: Two-fold astigmatism

▶ Run the image simulations. What is the effect on the probe?

Leave the image open. Change the azimuthal angle of two-fold astigmatism to  $\phi_{12} = 45^\circ$ .

▶ Run the simulation and compare the images.

### Set-up for exercise d: Three-fold astigmatism

↻ Set default values

- Experiment
  - Select IWRS
- Microscope settings
  - Unfold the nonsymmetrical aberrations of the condenser lens and set  $C_{23} = 5000 \text{ \AA}$

### Exercise d: Three-fold astigmatism

▶ Run the image simulations. What is the effect on the probe?

### Set-up for exercise e: Coma

↻ Set default values

- Experiment
  - Select IWRS
- Microscope settings
  - Unfold the nonsymmetrical aberrations of the condenser lens and set  $C_{21} = 25\,000 \text{ \AA}$

### Exercise e: Coma

- ▶ Run the image simulations. What is the effect on the probe?

MULTEM also allows you to add an aperture before the lens to limit and shape the incoming beam. The inner and outer radius of this aperture can be entered in milliradians (mrad). Increasing the size of this aperture allows higher angles to be used, and should result in a more focussed probe. However, experimentally the electrons scattered over high angles carry high order aberrations which cause a distortion of the probe.

### Set-up for exercise 3: Aperture outer radius

- ↻ Set default values
  - Experiment
    - Select IWRS

### Exercise 3: Aperture outer radius

- ▶ Run the image simulation.  
Leave the image open. Change the aperture outer angle from 21 mrad to 7 mrad.
- ▶ Run the image simulation.  
Leave the image open. Change the aperture outer angle to 50 mrad.
- ▶ Run the image simulation. Which aperture outer radius results in the best probe?  
Change the aberrations. Set for example  $C_{12} = 20 \text{ \AA}$ .
- ▶ Run the simulation again for the different aperture outer angles (7 mrad, 21 mrad, 50 mrad) and compare the images. Which aperture outer radius is now optimal?

### Set-up for exercise 4: Aperture inner radius

- ↻ Set default values
  - Experiment
    - Select IWRS
  - Microscope settings
    - Set the inner aperture radius equal to 18 mrad

### Exercise 4: Aperture inner radius

- ▶ Run the image simulation. You have now created a Bessel beam. Look at the phase.

### Set-up for exercise 5: Vortex beam

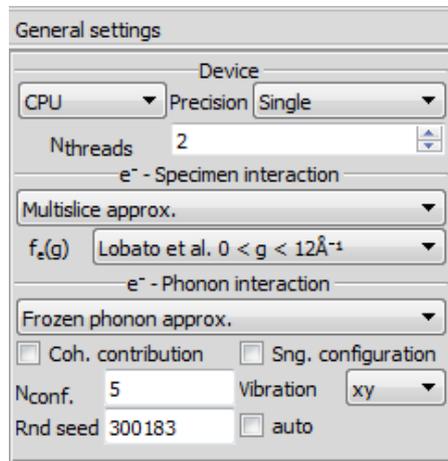
- ↻ Set default values
  - Experiment
    - Select IWRS

- Microscope settings
  - Set the vortex momentum equal to  $m = 1$

### Exercise 5: Vortex beam

- ▶ Run the image simulation. What is the effect on the probe?  
Leave the image open. Set  $m = 2$ .
- ▶ Run the simulation. What is the difference?  
Leave the image open. Set  $m = 0$ .
- ▶ Run the simulation. What is the difference? Compare all images by looking at Module as well as at the Phase.

## 2.2 General settings



**Figure 3:** The upper left panel of the MULTEM graphical user interface allows the user to implement some general settings concerning the computer and the type of image simulation.

MULTEM automatically detects whether or not your computer has a GPU. If no GPUs are detected, it will automatically choose CPU and detect the correct number of threads. You can choose between single and double precision. Usually, single precision is enough. Note that switching to double precision will increase the simulation time. This effect is usually small for modern 64-bit CPU, but simulation time can double for GPU.

In this panel, we also describe the electron-specimen interaction. You can choose between *multislice approximation*, *phase object approximation* and *weak phase object approximation*. The next drop-down menu allows you to select the parameterisation of the electron scattering factor you want to use.

### Set-up for exercise 6: Electron specimen interaction

↻ Set default values

- Specimen
  - o Load specimen\Cu001\_electron\_specimen\_interaction.txt

### Exercise 6: Electron specimen interaction

▶ Run the image simulation for the multislice approximation (default).

Leave the image you obtained open. Change the electron specimen interaction to the weak phase object approximation.

▶ Run the simulation.

Leave the image you obtained open again. Change the electron specimen interaction to the phase object approximation.

▶ Run the simulation. Compare the images. Can you explain the difference between them? Also look at the phase: check the box for Show Coherent wave in the image window, and select Phase instead of Module.

Finally we select the way the electron-phonon interaction is approximated: *frozen phonon approximation* or *still atom approximation*. The default will be set to the frozen phonon approximation with 5 configurations.

When you select frozen phonon, you can indicate whether or not you want to calculate the coherent contribution - which for a crystal is the Bragg scattering. Furthermore, you can indicate the number of phonon configurations you want to use in your calculations. If you want to look at the individual configurations, instead of the average of different configurations, you can indicate this by checking the box for *Sng. configuration*. You can also choose the direction of the vibration, which is set default to *xy*, which is most commonly used. Be careful when you choose vibrations along the *z* direction, since the slicing scheme will then change for each phonon configuration. Finally, you can enter a number in the box *Rnd seed*. This offers you the possibility to reproduce the same set of “random” configurations. If you just check the auto box, the software will work fine.

### Set-up for exercise 7: Electron phonon interaction

↻ Set default values

- General settings
  - o Change the electron phonon interaction to the still atom approximation
- Specimen
  - o Load specimen\Ag001\_electron\_phonon\_interaction.txt

### Exercise 7: Electron phonon interaction

▶ Run the image simulation for the still atom approximation.

Leave the image you obtained open. Change the electron phonon interaction to the frozen phonon approximation. Change the number of configurations to 1.

▶ Run the simulation. Compare the images. Do you understand the difference?

Leave the image you obtained open. Change the number of configurations to 5.

▶ Run the simulation.

Leave the image you obtained open. Change the number of configurations to 20.

▶ Run the simulation. Compare all images obtained with the frozen phonon approximation.

Do you understand the improvement?

## 2.3 Specimen

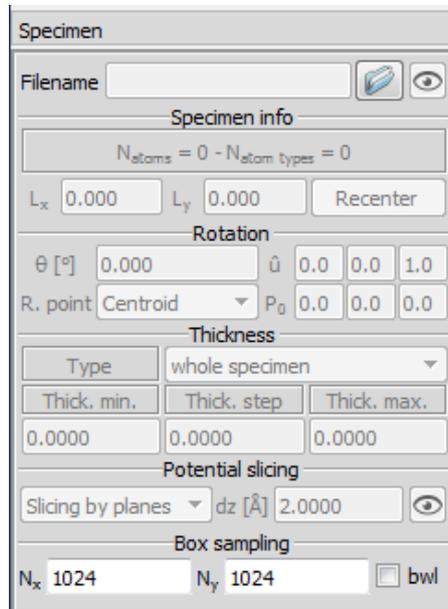
In this window, you can load a text file containing all information about your specimen. The file should have a specific format. The first row contains information about the simulation box size along x and y direction and the slice thickness. The subsequent rows contain information of each atom of the specimen:

- The first column specifies the type of atom (Z number).
- The next three columns specify the coordinates of the atom. Note that the x-y coordinates should be positive.
- In column 5, you can specify the root mean square displacement, which is related to the Debye-Waller factor (DWF) by the following formula  $rms = \sqrt{\frac{DWF}{8\pi^2}}$ .
- The entry in column 6 specifies the occupancy.
- In column 7, you can enter a number which can indicate different regions of the specimen. You can for example use different numbers to indicate atoms in the crystal and atoms in an amorphous region.
- Finally, column 8 allows you to indicate the charge of the atom.

The columns should be saved in a text file, such as the example shown in Table 1. You can produce the coordinates using other software such as CrystalMaker or construct them manually. When loading a file in MULTEM, you should make sure that the orientation of your specimen is along the z direction. If you want to study the incident wave, and thus omit the specimen, you can do this by selecting the *incident wave in real space (IWRs)* option in the simulation type item. Note that any specimen you may have already loaded will then be omitted from the graphical user interface.

10	10	2	0	0	0	0	0
79	0	0	0	0.085	1	0	0
79	2.039	2.039	0	0.085	1	0	0
79	4.078	0	0	0.085	1	0	0
79	0	4.078	0	0.085	1	0	0
79	4.078	4.078	0	0.085	1	0	0
79	0	2.039	2.039	0.085	1	0	0
79	2.039	0	2.039	0.085	1	0	0
79	4.078	2.039	2.039	0.085	1	0	0
79	2.039	4.078	2.039	0.085	1	0	0
79	0	0	4.078	0.085	1	0	0
79	2.039	2.039	4.078	0.085	1	0	0
79	4.078	0	4.078	0.085	1	0	0
79	0	4.078	4.078	0.085	1	0	0
79	4.078	4.078	4.078	0.085	1	0	0

**Table 1:** Example of a text file containing the sample info to load into MULTEM.



**Figure 4:** The lower left panel of the MULTEM graphical user interface allows the user to load all information about the specimen, increase the size of the simulation box, rotate the specimen, and determine the thickness, potential slicing and x-y sampling. The first line contains information about the simulation box size and slice thickness.

After loading the text file, the software will tell you the number of atoms  $N_{atoms}$  and the number of atomic types  $N_{atomic\ types}$  in the specimen as a feedback. Furthermore, the size of the simulation box, described by  $L_x$  and  $L_y$ , is automatically detected. This simulation box size should be such that there is periodicity in the x and y direction. However, if your purpose is to simulate a nanocrystal or nanoparticle, this periodicity is absent. In this case, you should change the size of the simulation box to add a sufficient amount of vacuum, and then push *recenter* to center your nanocrystal/nanoparticle in the box. This action fulfills the condition of the discrete Fourier transform. Note that the minimally required amount of vacuum increases with the specimen thickness.

### Set-up for exercise 8: Adding vacuum

☞ Set default values

- Specimen
  - Load specimen\Au001\_adding\_vacuum.txt
  - Set  $L_x = 50 \text{ \AA}$  and  $L_y = 50 \text{ \AA}$

### Exercise 8: Adding vacuum

After loading the specimen, MULTEM indicated that the size of the simulation box is  $L_x = 32.6240 \text{ \AA}$  and  $L_y = 32.6240 \text{ \AA}$ . In the set-up, you have added vacuum by increasing the size of the simulation box. In this way you perform a simulation for an isolated nanocrystal.

▶ Run the image simulation. Do you notice anything out of the ordinary? E.g. near the edge of the simulated image?

Leave the image window open. Now push the *recenter* button.

▶ Run the simulation again and compare your result.

The specimen can also be rotated. MULTEM allows you to describe *rotation angle*, *rotation vector* and *rotation point*. The latter can be chosen as the *centroid*, or entered manually. This option is especially useful for simulating nanocrystals or nanoparticles that are rotated with respect to the beam direction.

However, you should not use rotation to change the orientation of a periodic crystal. The rotated simulation box will be periodically repeated. This causes the thickness to vary throughout the crystal. Therefore, the result is not the periodic crystal in a different zone axis orientation. To load a different zone axis orientation, you should load another input file, obtained for example by rotating a supercell in a program such as CrystalMaker, and then cutting this specimen perpendicular to the required zone axis.

### Set-up for exercise 9: Rotation

☞ Set default values

- Specimen
  - Load specimen\Pt001\_rotation.txt
  - Set the rotation angle  $\theta = 45^\circ$

### Exercise 9: Rotation

▶ Run the image simulation. Is the result what you would have expected?

Leave the image open for comparison. Now add vacuum (set  $L_x = 70 \text{ \AA}$  and  $L_y = 70 \text{ \AA}$  and push the *recenter* button), in order to create a rotated **nanocrystal**.

▶ Run the image simulation. Compare the images.

The next part of this panel is the *thickness*. When simulating a nanocrystal or nanoparticle, we will simply use *whole specimen*. However, when simulating a crystal, the periodicity allows you to calculate different thicknesses in one calculation. This can be obtained by choosing *by thickness* in the drop-down menu. Once you have selected this option, three more boxes will appear. Through these boxes you can determine the *minimum thickness*, *step thickness*, and the *maximum thickness*.

MULTEM will automatically round the numbers you enter to the position of the nearest atomic layer. Note that increasing the number of thicknesses you want to obtain as an output from the simulation, will increase the needed memory and will therefore decrease the speed of the simulation.

### Set-up for exercise 10: Simulate crystal by thickness

↻ Set default values

- Specimen
  - o Load specimen\Au001\_thickness.txt
  - o Select *by thickness* instead of *whole specimen*
  - o Set *Thick. step* equal to 4.078 Å.

### Exercise 10: Simulate crystal by thickness

▶ Run the image simulation. Use the sliding bar at the top of the image window to look at the images for different thicknesses. What effect do you see?

### Set-up for exercise 11: Defocus

↻ Set default values

- Specimen
  - o Load specimen\Au\_nanoparticle\_defocus.txt
  - o Change the potential slicing to *slicing by dz* and leave the slice thickness at 2 Å

### Exercise 11: Defocus

▶ Run the image simulation for zero focus at the last atom (default).  
Leave the image open. Change to zero defocus at the first atom in the objective lens tab.  
▶ Run the image simulation.  
Leave the image open. Change to zero defocus in the middle of the specimen.  
▶ Run the image simulation. Compare the images to see the effect of defocus.

A very important part of this panel, which will only be activated when you chose the *multislice approximation* in the first window, is the *potential slicing*. An interesting feature of MULTEM is that it has an option to determine the slices automatically using the option *slicing by planes*. You can also determine the slicing yourself, by changing the drop-down menu to *slicing by dz* or *subslicing by dz*. In a future release, you will also be able to slice automatically. This will be particularly interesting if you have a simulation box with two different distances between your atomic planes, such as is for example the case in a diamond structures. Also in a future version, MULTEM will offer a visualisation of the chosen slicing when you click on the currently disabled eye shaped icon.

### Set-up for exercise 12: Potential slicing

↻ Set default values

- Specimen
  - o Load specimen\Au\_nanoparticle\_slicing.txt

- o Add vacuum to the simulation box (set  $L_x = L_y = 70 \text{ \AA}$ ) and push the recenter button
- o Choose *slicing by dz* and leave the slice thickness at  $2 \text{ \AA}$

### Exercise 12: Potential slicing

- ▶ Run the image simulation.
- Leave the image open for comparison. Now change to a slice thickness of  $20 \text{ \AA}$ .
- ▶ Run the simulation. Can you explain the difference?
- Change the potential slicing to slicing by planes.
- ▶ Run the simulation. What happens for this nanoparticle?

The last part of this specimen panel is the box sampling. MULTEM will round the number of sampling points you enter for  $N_x$  and  $N_y$  to the nearest number that is computationally efficient. Checking the *bwl* box will limit the bandwidth of the matrices involved in the multislice calculation. This means that high frequencies are cut off in Fourier space, such that they are not overlapping with themselves when they are periodically repeated. This avoids aliasing.

Furthermore, note that the number of sample points should be increased if the size of the simulation box is increased. A rule of thumb is to keep  $L_j/N_j \approx 0.05 \text{ \AA}$  for  $j=x,y$ , in order to correctly sample the potential.

### Set-up for exercise 13: Sampling

- ↻ Set default values
  - Specimen
    - o Load specimen\GaAs001\_sampling.txt
    - o Change the sampling to  $N_x=128$  and  $N_y=128$

### Exercise 13: Sampling

- ▶ Run the simulation and zoom in on an atomic column by scrolling with your mouse while hovering over the image.
- Leave the image open. Change the sampling back to 1024.
- ▶ Run the simulation and zoom in.

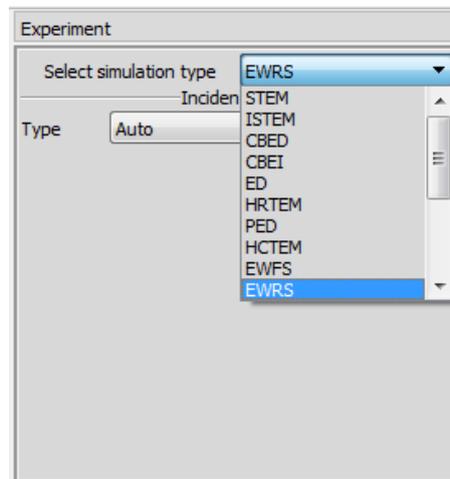
## 2.4 Experiment

In the *experiment* panel, the type of TEM experiment is selected and described. Possible simulation types currently provided in MULTEM are the following:

- Scanning transmission electron microscopy (*STEM*)
- Imaging scanning transmission electron microscopy (*ISTEM*)
- Convergent beam electron diffraction (*CBED*)
- Convergent beam electron imaging (*CBEI*)
- Electron diffraction (*ED*)
- High resolution transmission electron microscopy (*HRTEM*)

- Precession electron diffraction (*PED*)
- Hollow cone TEM (*HCTEM*)
- Exit wave in Fourier space (*EWFS*)
- Exit wave in real space (*EWRS*)
- STEM electron energy loss spectroscopy (*STEM\_EELS*)
- Energy filtered TEM (*EFTEM*)
- Incident wave in real space (*IWRS*)
- Projected potential in real space (*PPRS*)
- Transmission function in real space (*TFRS*)

Whichever of these simulation types you choose, there is always an *Auto* option, which represents the most commonly used incident wave.



**Figure 5:** The upper right panel of the MULTEM graphical user interface allows the user to select the type of TEM experiment, and provide details about the experiment set-up.

We will discuss the features of *HRTEM*, *ED*, *STEM* and *EFTEM*. The other simulation types fall outside the scope of this tutorial.

The *HRTEM* option is fairly straightforward. You can select the incident wave, with choices between *auto*, *plane wave* or *user define*. The latter will require you to load a binary file with a complex matrix describing the incident wave.

### Set-up for exercise 14: High resolution transmission electron microscopy

#### ☞ Set default values

- Specimen
  - Load specimen\Si001\_HRTEM.txt
  - Select *by thickness* instead of *whole specimen*
  - Set *Thick. step* equal to 5.4307 Å.
- Experiment

- o Select HRTEM

#### Exercise 14: High resolution transmission electron microscopy

- ▶ Run the image simulation. Scroll through the images for different thicknesses.

Also the ED option is fairly straightforward. You can select the incident wave, with choices between *auto*, *plane wave* or *user define*. The latter will again require you to load a binary file with a complex matrix describing the incident wave.

#### Exercise 15: Electron diffraction

##### Set-up for exercise a: Diffraction spots

- ↻ Set default values
  - Specimen
    - o Load specimen\Si001\_ED.txt
    - o Select *by thickness* instead of *whole specimen*
    - o Set *Thick. step* equal to 5.4307 Å.
  - Experiment
    - o Select ED

##### Exercise a: Diffraction spots

- ▶ Run the image simulation. Scroll through the images for different thicknesses.

##### Set-up for exercise b: Kikuchi lines

- ↻ Set default values
  - Specimen
    - o Load specimen\Au001\_thickness.txt
    - o Select *by thickness* instead of *whole specimen*
    - o Set *Thick. step* equal to 4.078 Å.
  - Experiment
    - o Select ED

##### Exercise b: Kikuchi lines

- ▶ Run the image simulation. Scroll through the images for different thicknesses. Try to look at the image with jet colorscale or play with the scaling to enhance the contrast.

When using the STEM option, not only the incident wave can be given as input, but some input about the scanning pattern and the detectors is required as well. You can choose between a *line* scan or an *area* scan. An input field allows you to define the number of scan points  $N_{scans}$ . The drop-down menu selects the scanning direction: *max*,  $L_x$  or  $L_y$ , where the first option will select the largest out of  $L_x$  and  $L_y$ . Next to this drop-down menu, you see a check box for *psc*. Checking this means you want to exclude the last scan point from your simulation box. This option should be used in case of a periodic crystal, since in that case the last point is the same as the first point of the simulation box. In order to fully describe the scanning pattern, you need to indicate the starting and ending point of the scan. This can be done by entering the x and y positions in Å. In a future version of MULTEM you will be able to select this area on a figure by clicking on the button next to the input fields, which is currently still disabled.

MULTEM allows you to simulate using one or multiple detectors. You can enter the inner and outer angle (in mrad) for each detector by changing the number of the detector  $N_{det}$  using the drop-down menu. Furthermore you can choose whether your detector is ideal or if you want to upload a matrix with your custom detector. MULTEM provides a visualisation of your detector(s).

Note that you need to input a large crystal, and then afterwards select a small area to scan. Starting with such a large crystal is necessary for three reasons: to avoid self-interaction of the probe, to ensure periodicity since different phonon configurations break periodicity over small areas, and to self contain the probe which broadens with the thickness when traveling through the specimen. In the resulting image, you can replicate the simulated scanned area, since it is periodic. You replicate by changing the numbers Rep. x and Rep. y at the lower left bottom of the image window which opens after you finished your simulation.

### Set-up for exercise 16: Scanning transmission electron microscopy

☞ Set default values

- Specimen
  - o Load specimen\SrTiO3001\_STEM.txt
  - o Change the sampling to  $N_x=512$  and  $N_y=512$
- Experiment
  - o Select STEM
  - o Set the number of scan points  $N_{scans}=5$
  - o Define the area to scan:  $X_0 = 11.7150 \text{ \AA}$ ,  $X_e = 15.6200 \text{ \AA}$ ,  $Y_0 = 11.7150 \text{ \AA}$ , and  $Y_e = 15.6200 \text{ \AA}$ .

### Exercise 16: Scanning transmission electron microscopy

▶ Run the image simulation.

Replicate the image by changing Rep. x and Rep. y at the lower left bottom of the image window to 3. Center the image by double clicking on it.

Leave the image open. Now change the number of scan points to 20.

▶ Run the simulation. Replicate the image by changing Rep. x and Rep. y at the lower left bottom of the image window to 3. Center the image by double clicking on it. What difference do you see?

Add a second detector with inner angle 0 mrad and outer angle 20 mrad. Set the number of scan points  $N_{scans}=10$ .

▶ Run the simulation. Look at the images obtained by both detectors. Scroll through the images for different detectors using the sliding bar at the top of the image window.

The EFTEM option requires the type of incident wave, and some information about the Energy Loss. You can select the element you are interested in, using a drop-down menu, as well as the energy for that element. You can indicate the angle in mrad that determines the size of the objective aperture, the mixed dynamic object spectrum (MDOS) selection rule and the approximation: single channelling, mixed channelling or double channelling.

### Set-up for exercise 17: Energy filtered transmission electron microscopy

↻ Set default values

- Specimen
  - Load specimen\SrTiO3001\_EFTEM.txt
  - Change the sampling to  $N_x=512$  and  $N_y=512$
- Experiment
  - Select EFTEM
  - Select *Element* to Sr
  - Change *Energy* edge to 1940
  - Select double channelling approximation.

### Exercise 17: Energy filtered transmission electron microscopy

▶ Run the image simulation.

Leave the image open. Now change *Element* and *Energy* edge to O and 532, respectively.

▶ Run the simulation. What difference do you see?

## References

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- [Lobato and Van Dyck, 2015] Lobato, I. and Van Dyck, D. (2015). MULTEM: A new multislice program to perform accurate and fast electron diffraction and imaging simulations using Graphics Processing Units with CUDA. *Ultramicroscopy*, 156:9–17.